SHOP-FLOOR DISPATCHING SYSTEM BASED ON VOTING SCHEME FOR SEMICONDUCTOR WAFER FABRICATION

ABSTRACT OF THE DISCLOSURE

In a manufacturing control system for computer control of work flow in an automatic manufacturing production line with a plurality of work stations at which the progress of work is monitored, priority ratings are assigned to each lot of WIP materials with the priority ratings ranging from low to high. The priority rating of a lot increases as a function of increasing queue time, and as a function of the difference comprising the expected date out minus commitment date. The priority rating is reset to a default value after the lot is run. The passage of WIP materials is clocked to measure depletion and accumulation of material at a work station with increases in priority rating as a function of the difference of target velocity minus actual velocity of work with an increase of one priority rating level as the cumulative value of the difference exceeds a predetermined percentage.

(FIGURE 1 IS SUGGESTED FOR PUBLICATION)